

Docket No.: YOR9200305450US1
20140-00317
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Ying Zhang et al.

Application No.: 10/730,891

Confirmation No.: 5178

Filed: December 10, 2003

Art Unit: 2812

For: A NEW METHOD OF ETCHING DUAL PRE-
DOPED POLYSILICON GATE STACKS
USING CARBON-CONTAINING GASES
ADDITIONS

Examiner: A. Mustapha

RESPONSE UNDER 37 C.F.R. 1.116 (FINAL OFFICE ACTION)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This is in response to the final Office Action mailed on May 11, 2007 in the above-captioned case.

Amendments to the Claims are reflected in the Listing of Claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.